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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Applicant(s): NABESHIMA et al. | Atty. Docket: PA214WP002 |
| Serial No.: 10/598,933 | Group Art Unit: n/a |
| Filed: 14 September 2006 | Examiner: n/a |
| Title: SEMICONDUCTOR WAFER INSPECTION DEVICE AND METHOD | |

Date: March 19, 2007

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Mail Stop: Amendment

PRELIMINARY AMENDMENT

Sir:

Pursuant to 37 C.F.R. 1.115 and M.P.E.P. § 714.09, the Applicant wishes to file this
PRELIMINARY AMENDMENT to the above-identified application.

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 3 of this paper.